

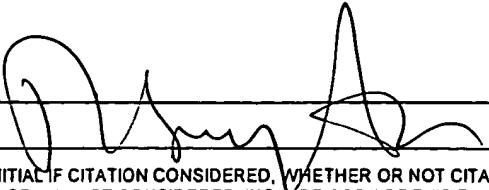
 <p>U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</p> <p>MAY 17 2003 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)</p>	ATTY. DOCKET NO. MICRON.098DV2	APPLICATION NO. 10/614,418
	APPLICANT Basceri, et al.	
	FILING DATE July 3, 2003	GROUP 2831

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
NH	1	5,581,436	12/03/96	Summerfelt et al.	361	321.1	
NH	2	6,285,051	09/04/01	Ueda et al.	257	296	

FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
NH	3	WO 95/25340	09/21/95	EP			YES NO

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)			
NH	4	Joo, "Fabrication and Characterization of MOCVD (Ba, Sr)TiO ₃ Thin Films for High Density Capacitors", Proceeding of 1997 5th International Conference an VLSI and CAD", The Secretariat of ICVC '97, 1997.		

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050704

EXAMINER	DATE CONSIDERED
	
<p>*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609. DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.</p>	

FORM PTO-1449 E JCB 202003 MARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT USE SEVERAL SHEETS IF NECESSARY)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MICRON.098DV2	APPLICATION NO. 10/614418
		APPLICANT Basceri et al.	
		FILING DATE July 3, 2003	GROUP Hakneaw 2831



U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

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101003

EXAMINER  DATE CONSIDERED 1/15/25